

PLASMA PROCESSING APPARATUS

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ABSTRACT OF THE DISCLOSURE

A plasma processing apparatus for supplying microwaves into a process chamber so as to generate plasma, to thereby treat an object to be processed with the plasma. In the plasma processing apparatus, the process chamber has a top plate which is disposed opposite to the object to be processed, through the medium of a region for generating the plasma; and the top plate has at least one antenna which is disposed so that the antenna penetrates the top plate into the inside of the process chamber.